



#5/IPS Division
12-11-01

Sheet 1 of 2

U.S. Department of Commerce, Patent and Trademark Office						Atty Docket No.		Serial No.	
						M-9367 US		09/788,273	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT						Applicant(s)			
(Use several sheets if necessary)						Borden, Peter G.; Li, Ji-Ping			
						Filing Date		Group	
						February 16, 2001		2812 2823	
U.S. Patent Documents									
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate		
<i>me</i>	AA	4,255,971	3/17/1981	Rosencwaig	73	606			
<i>me</i>	AB	4,579,463	4/1/1986	Rosencwaig et al.	374	57			
<i>me</i>	AC	4,632,561	12/30/1986	Rosencwaig et al.	356	432			
<i>me</i>	AD	4,636,088	1/13/1987	Rosencwaig et al.	374	5			
<i>me</i>	AE	4,750,822	6/14/1988	Rosencwaig et al.	356	445			
<i>me</i>	AF	4,854,710	8/8/1989	Opsal et al.	356	432			
<i>me</i>	AG	4,950,990	8/21/1990	Moulder et al.	324	224			
<i>me</i>	AH	4,952,063	8/28/1990	Opsal et al.	356	432			
<i>me</i>	AI	5,042,951	8/27/1991	Gold et al.	356	369			
<i>me</i>	AJ	5,042,952	8/27/1991	Opsal et al.	356	432			
<i>me</i>	AK	5,159,412	10/27/1992	Willenberg et al.	356	445			
<i>me</i>	AL	5,181,080	1/19/1993	Fanton et al.	356	381			
<i>me</i>	AM	5,228,776	7/20/1993	Smith et al.	374	5			
<i>me</i>	AN	5,667,300	9/16/1997	Mandelis et al.	374	43			
<i>me</i>	AO	6,049,220	4/11/2000	Borden et al.	324	765			
<i>me</i>	AP	6,054,868	4/25/2000	Borden et al.	324	752			
Foreign Patent Documents									
							Translation		
		Document	Date	Country	Class	Subclass	Yes	No	
<i>me</i>	AQ	WO 97/08536	6 March 1997	PCT	G01N	21/00			
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
<i>me</i>	AR	Amirtharaj and Seiler, "Optical Properties of Semiconductors," Handbook of Optics, Vol. II, McGraw-Hill, Inc., 1995, pp. 36.67-36.68, 36.95 and Table 11. (Exerpt).							
<i>me</i>	AS	Borden, Peter G. et al., "Evaluating A Property of A Multilayered Structure," U.S. Patent Application No. 09/521,232, filed on 3/8/00.							
Examiner		<i>Michelle Estrada</i>		Date Considered		3/13/03			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.									

U.S. Department of Commerce, Patent and Trademark Office		Atty Docket No.	Serial No.
		M-9367 US	09/788,273
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Applicant(s)	
(Use several sheets if necessary)		Borden, Peter G.; Li, Ji-Ping	
		Filing Date	Group
		February 16, 2001	2812 2823
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)			
<i>ME</i>	AT	Eikelboom, J.A. et al., "Microwave Detection of Minority Carriers in Solar Cell Silicon Wafers," <u>Solar Energy Materials and Solar Cells</u> , Elsevier Science B.V., Oct. 1995, pp. 169-185.	
<i>ME</i>	AU	Grove, A.S., "Physics and Technology of Semiconductor Devices," John Wiley & Sons, Inc., 1967, p. 326.	
<i>ME</i>	AV	Jackson, John David, "Classical Electrodynamics," John Wiley & Sons, Inc., 1962, pp. 222-226.	
<i>ME</i>	AW	Kolzer, J. et al., "Thermal Imaging and Measurement Techniques for Electronic Materials and Devices," <u>Microelectronics Engineering</u> , vol. 31, 1996, pp. 251-270, XP004006637, Elsevier Publishers BV., Amsterdam, NL, ISSN: 0167-9317.	
<i>ME</i>	AX	Martinsons, Christophe et al., "Recent progress in the measurement of the thermal properties of hard coatings," <u>Thin Solid Films</u> , vol. 317, April 1998, pp. 455-457, XP004147705, Elsevier-Sequoia S.A. Lausanne, CH, ISSN: 0040-6090.	
<i>ME</i>	AY	Opsal et al., "Thermal-Wave Detection and Thin-Film Thickness Measurements with Laser Beam Deflection," <u>Applied Optics</u> , Vol. 22, No. 20, Oct. 1983, pp. 3169-3176.	
<i>ME</i>	AZ	Orton, J.W. et al., "The Electrical Characterization of Semiconductors: Measurement of Minority Carrier Properties," Academic Press, 1990, pp. 94-100.	
<i>ME</i>	BA	Paquin, "Properties of Metals," <u>Handbook of Optics</u> , Vol. II, McGraw-Hill, Inc., 1995, pp. 35.3-35.7 (Exerpt).	
<i>ME</i>	BB	Rosencwaig, Allan et al., "Detection of thermal waves through optical reflection," <u>Appl. Phys. Lett.</u> 46, June 1985, pp. 1013-1015.	
<i>ME</i>	BC	Rosencwaig, Allan, "Thermal Wave Characterization and Inspection of Semiconductor Materials and Devices," <u>Photoacoustic and Thermal Wave Phenomena in Semiconductors</u> , Chapter 5, pp. 97-135, North-Holland, 1987.	
<i>ME</i>	BD	Rosencwaig, Allan, "Thermal-Wave Imaging," <u>Science</u> , Vol. 218, No. 4569, Oct. 1982, pp. 223-228.	
<i>ME</i>	BE	Schroder, Dieter K., "Semiconductor Material and Device Characterization," John Wiley & Sons, Inc., 1990, pp. 2-20, 84-85, 232-235, 304-306, 364, 367-374, 378-383.	
<i>ME</i>	BF	Sze, S.M., "Physics of Semiconductor Devices," John Wiley & Sons, Inc., 1981, pp. 50-51.	
<i>ME</i>	BG	"Process Monitoring System," Quantox Product Brochure, 3 pgs.	
Examiner <i>Michelle Estrada</i>		Date Considered <i>3/13/03</i>	
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.			